Amendments To The Cinims

Please cancel Claims 1 and 14-18 without prejudice. The following list of the claims replaces all prior versions and lists of the claims in this application.

Claim I (Canceled).

- 2. (Currently amended) The capacitor device recited in Glaim 4 wherein the third electrode is located over the first and second electrodes.
- 3. (Currently amended) The capacitor device recited in Claim 4 further comprising a third insulating layer located over the third electrode, wherein the first and second interconnects are located over the third insulating layer.
- 4. (Currently amended) The capacitor device recited in Claim 1 wherein: A capacitor device, comprising:
 - a first electrode located over a substrate and connected to a first interconnect;
 - a first insulating layer located over the first electrode;
- a second electrode located over the first insulating layer and connected to a second interconnect;
 - a second insulating layer located over the second electrode; and
- a third electrode located over the second insulating layer and connected to the first interconnect:

wherein the first electrode and the first interconnect are connected by a first via; the second electrode and the second interconnect are connected by a second via; and the third electrode and the first interconnect are connected by a third via.

 (Original) The capacitor device recited in Claim 4 wherein at least one of the first, second and third vias and at least one of the first and second interconnects are collectively a dualdamascene structure.

- 6. (Currently amended) The capacitor device recited in Claim 4 Claim 4 wherein the first insulating layer includes an insulation layer and an each stop layer located over the insulation layer.
- 7. (Currently Amended) The capacitor device recited in Claim 4 wherein a first-perimeter of the first electrode envelopes a second perimeter of the second electrode the second electrode is within a perimeter of the first electrode when viewed in a direction perpendicular to the first and second electrodes.
- 8. (Currently Amended) The capacitor device recited in Claim 7 wherein the secondperimeter envelopes a third perimeter of the third electrode the third electrode is within a perimeter
 of the second electrode when viewed in a direction perpendicular to the second and first
 electrodes.
- 9. (Currently amended) The capacitor device recited in Claim 1 Claim 4 wherein the first electrode comprises copper.
- 10. (Currently amended) The capacitor device recited in Claim 4 wherein the second and third electrodes each comprise a same one selected from the group consisting of:

tungsten;

tungsten silicide;

aluminum;

titanium: and

titanium nitride.

11. (Currently amended) The capacitor device recited in Claim 1 Claim 4 wherein the second and third electrodes each include a plurality of conductive layers.

- 12. (Currently amended) The capacitor device recited in Claim 4 wherein a total unit capacitance of the capacitor device ranges between about 1.3 fF/μm² and about 2.0 fF/μm².
- 13. (Currently amended) The capacitor device recited in Claim 4 wherein a total unit capacitance of the capacitor device is about 1.5 fF/μm².

Claims 14 to 18 (Canceled).

- 19. (Currently amended) A semiconductor device, comprising:
- a transistor element located over a substrate and having a contact;
- a capacitor element, including:
 - a first electrode located over the substrate;
 - a first insulating layer located over the first electrode;
 - a second electrode located over the first insulating layer,
 - a second insulating layer located over the second electrode; and
 - a third electrode located over the second insulating layer;
- a dielectric layer located over the transistor element and the capacitor element;
- a first interconnect located over the dielectric layer, coupled to the first electrode by a first via, and coupled to the third electrode by a second via; and
- a second interconnect located over the dielectric layer, coupled to the second electrode by a third electrode by a third via, and coupled to the transistor contact by a fourth via.
- 20. (Original) The semiconductor device recited in Claim 19 wherein the first interconnect and the first and second vias are collectively a dual-damascene structure.
- 21. (Original) The semiconductor device recited in Claim 19 wherein the second interconnect and the third and fourth vias are collectively a dual-damascene structure.

- 22. (Original) The semiconductor device recited in Claim 19 wherein the first insulating layer includes an insulation layer and an etch stop layer located over the insulation layer.
- 23. (Original) The semiconductor device recited in Claim 19 wherein the first electrode comprises copper.
- 24. (Original) The semiconductor device recited in Claim 19 wherein the second and third electrodes each comprise a same one selected from the group consisting of:

tungsten;

tungsten silicide;

aluminum;

titanium; and

titanium nitride.

25. (Original) The semiconductor device recited in Claim 19 wherein the second and third electrodes each include a plurality of conductive layers.